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PATENT  
2557-000177/US

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANTS: Chang Won CHOI et al. CONF. NO.: 5346  
SERIAL NO.: 10/762,526 GROUP: 1792  
FILED: January 23, 2004 EXAMINER: Lund, Jeffrie R.  
FOR: WAFER EDGE ETCHING APPARATUS AND METHOD

**AMENDMENT**

Customer Service Window  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314  
**Mail Stop Amendment**

May 16, 2008

Dear Sir:

Responsive to the Official Action dated November 16, 2007, the due date having been extended three (3) months to May 16, 2008, the following amendments and remarks are respectfully submitted in connection with the above-referenced application.

**Amendments to the claims** begin on page 2 of this paper.

**Remarks** begin on page 11 of this paper.

	Claims remaining after Amendment		Highest number previously paid for		Present extra
Total	44	-	44	=	0
Independent	6	-	6	=	0

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